

1764



PATENT  
5480-00201/OP99140\_US-CPA

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:  
Dong-soo Kim

Serial No 09/287,602

Filed: April 7, 1999

For: GAS SCRUBBER FOR TREATING  
THE GAS GENERATED DURING THE  
SEMICONDUCTOR  
MANUFACTURING PROCESS

Group Art Unit: 1764

Examiner: Tran, H.

Atty. Dkt. No. 5480-00201

#120  
8/30/02  
MW

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Assistant Commissioner for Patents, Washington, D.C. 20231, on  
the date indicated below:

8/13/02

Date

Kevin L. Daffer

**AMENDMENT; RESPONSE TO OFFICE ACTION MAILED MAY 17, 2002**

**Box: Non-Fee Amendment**  
Assistant Commissioner for Patents  
Washington, D.C. 20231

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Dear Sir/Madam:

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This paper is submitted in response to the Office Action mailed May 17, 2002 to further highlight reasons why the application is in condition for allowance.

Please amend the case as follows.

**IN THE SPECIFICATION**

Please replace pg. 6, line 23 - pg. 7, line 2, of the amended Specification (Attachment A of the Response to the Office Action mailed October 4, 2000) with the amended paragraph below. A "marked-up" version of each amendment is included in **Attachment A**.